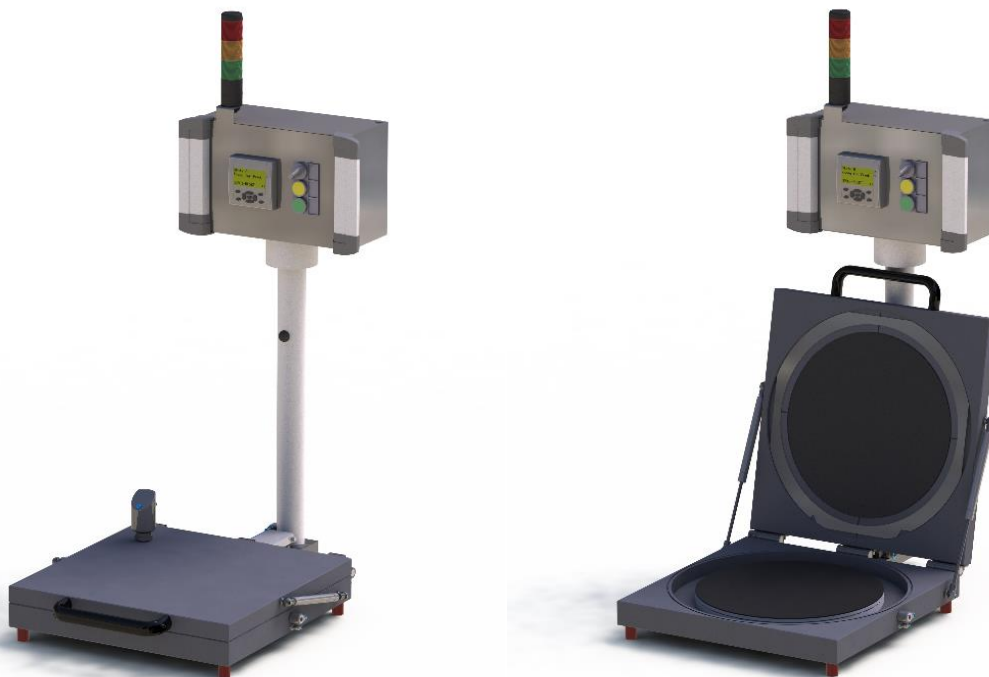


## Semi-Automatic Vacuum Wafer Mounter V-300



POWATEC's V-300 Wafer Mounter is a highly specialized semi-automatic device for highest requirements in adhesion results of 300mm wafers or substrates onto a frame mounted film. It is mostly used in advanced research and development departments or series production of large companies. The personnel can achieve a throughput of up to 60 mounts per hour with minimal instruction. The strength of the V-300 lies in:

- The highly reproducible top-quality results
- Highest requirements for homogeneous and concentric lamination of flat wafers or substrates
- Controlled, highly reproducible and minimal force exertion onto the wafer or substrate

Whether silicon wafers or glass, ceramics, FR4, Kapton or other substrates - there are almost no limits to the variety of wafers or substrates to be processed. POWATEC can customize the modular V-300 for your process requirements even for Taiko wafers or wafer bonding.

The extremely short set-up times, low operating costs, slim dimensions and the qualitatively outstanding and reproducible end-results for special applications have made the V-300 a product of great international demand in clean room applications for over a decade.

## Product Features

- 60-80 seconds per mount
- Vacuum performance 3 mbar absolute (-1 bar)
- Automatic process consists of vacuum generation and controlled mounting
- Adjustable mounting speed
- Display of mounting vacuum
- Table-top device
- Applicable for clean room application

## Unique Selling Proposition

- The highly reproducible top-quality results
- Highest requirements for homogeneous and concentric lamination of flat wafers or substrates
- Controlled, highly re-producible and minimal force exertion onto the wafer or substrate
- Minimal maintenance (< 100 USD per year)

## Chamber Dimensions & Mechanical Specification

Wafer-size:	up to 300 mm
Frame-size:	up to 300 mm
Frame Type:	Disco and K&S, Steel Material only
Width:	470 mm
Height:	1100 mm
Depth:	750 mm
Weight:	40kg

## Electrical Specification

Main power		110-240 VAC, 50/60 Hz
Power supply for control unit	Input	85-240 VAC
	Output	24 VDC/1.5A
	Power	max. 25 W

## Pneumatic Specification

Required vacuum	8 mbar absolute
Vacuum connection	Festo PUN-8, Ø8 mm
Required air pressure	4-6 bar
Pressure connection	Festo PUN-6, Ø6 mm

Accessory



**Vacuum-Pump**

0.55KW, 220-240V, 50/60 Hz

Comes with active carbon filter and exhaust particle remover designed from POWATEC for clean room application

Conformity

Build according to IEC 204-1

CE marking

Related Products from POWATEC



**Manual Wafer Mounter P-300**

Mounting of up to 300mm Wafer onto 300mm Film Frame



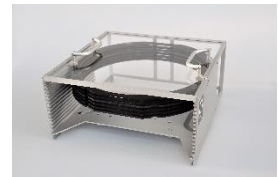
**UV Flash Curing System UF-300**

Curing of up to 300mm Wafer onto 300mm Film Frame



**Vacuum Wafer Mounter V-300**

Mounting of up to 300mm Wafer onto 300mm Film Frame



**Wafer Frame Magazine**

300mm Wafer onto 300mm Film Frame, 13 or 25 slots